



2823
Docket: 740756-1894

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of)
Shunpei YAMAZAKI et al.) Group Art Unit: 2823
Serial No. 09/197,534) Examiner: W. David Coleman
Filed: November 23, 1998) Allowed: September 10, 2003
For: Laser Process) Date: October 21, 2003

**REQUEST FOR ACKNOWLEDGMENT OF
INFORMATION DISCLOSURE STATEMENT**

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

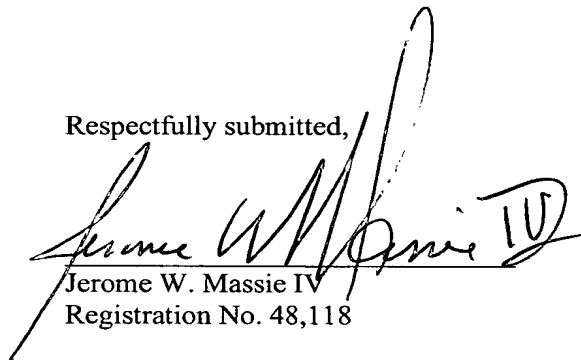
Sir:

Information Disclosure Statements with Forms PTO-1449 were filed in the above-identified patent application on June 15, 2000, December 19, 2000 and August 20, 2003. Applicants have not yet received back from the Examiner a copy of the Forms PTO-1449 initialed to acknowledge the fact that the Examiner has considered the cited disclosed information.

The Examiner is requested to initial and return to the undersigned a copy of the subject Forms PTO-1449.

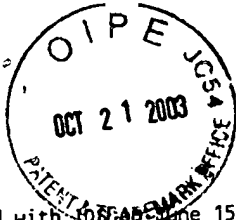
Should there be any questions concerning this communication, please telephone the undersigned at the number set forth below.

Respectfully submitted,



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Submitted with USPTO Form 15, 2000

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Form PTO-1449
(Rev. 8-83)U.S. Department of Commerce
Patent and Trademark OfficeAtty.Docket No.
0756-1894Serial No.
09/197,534**INFORMATION DISCLOSURE STATEMENT**

(Use several sheets if necessary)

Applicant
Shunpei Yamazaki et al.Filing Date
November 23, 1998Group
2874**U.S. PATENT DOCUMENTS**

Examiner Initial	Document Number	Date	Name	Class	Subclass	Filing Date (if appropriate)
	3,667,832	06/72	Kitano et al.			
	4,436,557	03/13/84	Wood et al.			
	4,475,027	10/02/84	Pressley			
	4,484,334	11/84	Pressley			
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	4,546,009	10/08/85	Tiedje et al.			
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	4,733,944	03/29/88	Fahlen et al.			
	4,769,750	09/06/88	Matsumoto et al.			

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					Yes	No
176715	03/89	Japan			Abst.	
220681	01/24/90	Japan			Abst.	
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OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)

	Pennington, K.S. et al., "CCD Imaging Array Combining Fly's Eye Lens with TDI for Increasing Light-gathering Ability", IBM Technical Disclosure Bulletin, Vol. 21, No.2, July 1978, pp. 857-858.
	"Crystallization of Amorphous Silicon by Excimer Laser Annealing with a Line Shape Beam Having A Gaussian Profile", Young Min Jhon et al., Jpn. J. Appl. Phys. Vol. 33 (1994), pp. L1438-1441
	"Enlargement of Poly-Si Film Grain Size by Excimer Laser Annealing and its Application to High-Performance Poly-Si Thin Film Transistor", Hiroyuki Kuriyama et al., Jpn. J. App. Phys., Vol. 30, No. 12B, December, 1991, pp. 3700-3703.
	"Formation of p-n Junctions and Silicides in Silicon Using a High Performance Laser Beam Homogenization System", M. Wagner et al., Applied Surface Science 43 (1989), pp. 260-263.

Examiner

Date Considered

*EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

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Submitted with IDS on June 15, 2000

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PATENT & TRADEMARK OFFICE
Form PTO-1449
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2294027	12/05/90	Japan			Abst.
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	"Lateral Grain Growth of Poly-Si Films with a Specific Orientation by an Excimer Laser Annealing Method", Hiroyuki Kuriyama et al., Jpn. J. Appl. Phys. Vol. 32 (1993), Pt. 1, No. 12B, pp. 6190-6195.
	"P-28: 3.7-in.-Diagonal STN-LCD with Stripe Electrode Patterns Fabricated by an Excimer-Laser Scribing System" T. Konuma et al., Semiconductor Energy Laboratory Co., Ltd., 550. SID 93 Digest.
	"Poly-Si by Excimer Laser Annealing with Solidification Process Control", Shigeru Noguchi et al., C-II, Vol. J76-C-II, No. 5, 1993, pp. 241-248.

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Form PTO-1449 (Rev. 8/78)		U.S. Department of Commerce Patent and Trademark Office		Atty.Docket No. 0756-1894		Serial No. 09/197,534	
INFORMATION DISCLOSURE STATEMENT (Use several sheets if necessary)				Applicant Shunpei Yamazaki et al.			
				Filing Date November 23, 1998		Group 2874	
U.S. PATENT DOCUMENTS							
Examiner Initial	Document Number	Date	Name	Class	Subclass	Filing Date (if appropriate)	
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	5,236,865	08/17/93	Sandhu et al.				
	5,263,250	11/93	Nishiwaki et al.				
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	5,307,207	04/26/94	Ichihara				
	5,372,836	12/13/94	Imahashi et al.				
	5,413,958	05/09/95	Imahashi et al.				
	5,432,122	07/11/95	Chae				
	5,456,009 <i>5/B 4, 5/10/00</i>	10/08/85	Tiedje et al.				
FOREIGN PATENT DOCUMENTS							
	Document Number	Date	Country	Class	Subclass	Translation Yes No	
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	Enlargement of Poly-Si film Grain Size by Excimer laser Annealing and its Application to High-performance Poly-Si Thin Film Transistor", hiroyuki Kuriyama et al., Jpn J. App. Phys., Vol. 30, No. 12B, December, 1991, pp. 3700-3703.						
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OFFICE 1449
(Rev. 8-83)U.S. Department of Commerce
Patent and Trademark OfficeAtty.Docket No.
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U.S. PATENT DOCUMENTS

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	5,708,252	01/98	Shonohara et al.			
	5,858,473	01/12/99	Yamazaki et al.			

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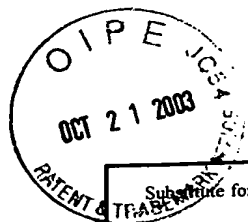
Document Number	Date	Country	Class	Subclass	Translation Yes No	

OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)

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Date Considered:

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Substitute for form 1449A/PTO INFORMATION DISCLOSURE STATEMENT BY APPLICANT (use as many sheets as necessary)				Complete if Known	
				Application Number	
				Filing Date	
				First Named Inventor	
				Art Unit	
				Examiner Name	
Sheet	1	of	1	Attorney Docket Number	740756-1894

U.S. PATENT DOCUMENTS					
Examiner Initials*	Cite No. ¹	U.S. Patent Document	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear
		Number - Kind Code ² (if known)			
		US-			
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FOREIGN PATENT DOCUMENTS							
Examiner Initials ²	Cite No. ¹	Foreign Patent Document		Publication Date MM-DD-YYYY	Name of Patentee or Application of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear	T ⁴
		Country Code ³	Number ⁴ Kind Code ⁵ (if known)				
		JP	2-187294	07/23/1990	KAJIKAWA		AB

OTHER PRIOR ART - NON PATENT LITERATURE DOCUMENTS			
Examiner Initials ²	Cite No. ¹	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	T ²
		Itoga et al. "Laser Re-Crystallization Utilizing Beam Homogenizing Optical System" Japan Society of Applied Physics, Proceedings of 48 th Annual Meetings, 2 nd Part, 18 p-6-N-6, P. 537 (1987)	

Examiner Signature	Date Considered
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¹ Applicant's unique citation designation number (optional). ² See Kinds Codes of USPTO Patent Documents at www.uspto.gov or MPEP 901.04. ³ Enter Office that issued the document, by the two-letter code (WIPO Standard ST.3). ⁴ For Japanese patent documents, the indication of the year of the reign of the Emperor must precede the serial number of the patent document. ⁵ Kind of document by the appropriate symbols as indicated on the document under WIPO Standard ST.16 if possible. ⁶ Applicant is to place a check mark here if English language Translation is attached.

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